

**PATTERSON &
SHERIDAN, LLP**
— ATTORNEYS AT LAW

3040 Post Oak Blvd, Suite 1500
Houston, TX 77056-6582
TEL 713.623.4844
FAX 713.623.4846

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DATE: August 22, 2006
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Examiner Ram N. Kackar
FAX NO: 571-273-8300
COMPANY: USPTO
FROM: Nywell A. Houston
Legal Assistant to Keith Tackett
PAGE(S) with cover: 5
ORIGINAL TO FOLLOW? ☐ YES ☒ NO

NOTICE OF APPEAL; PETITION FOR TWO MONTH EXTENSION OF TIME

TITLE: Method and System for Monitoring an Etch Process
U.S. SERIAL NO.: 10/674,568
FILING DATE: September 29, 2003
INVENTOR: Matthew Fenton Davis, et al.
EXAMINER: Ram N. Kackar
GROUP ART UNIT: 1763
CONFIRMATION NO.: 3852

CONFIDENTIALITY NOTE

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